

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE  
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APPLICANT  
Setsuo KAJIWARA et al.FILING DATE  
March 12, 2004GROUP  
1742

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
GW	AA	6,001,195	12/1999	KajiwarA et al.			
GW	AB	5,547,633	8/1996	Muddle et al.			
GW	AC	4,919,177	4/1990	Homma			
GW	AD	5,350,468	9/1994	Masumoto et al.			
GW	AE	5,306,363	4/1994	Masumoto et al.			
GW	AF	5,178,689	1/1993	Okamura et al.			
GW	AG	5,069,731	12/1991	Yoshizawa et al.			
GW	AH	5,149,381	9/1992	Grewe et al.			
	AI						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO	
	AJ							
	AK							

## OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

GW	AL	Merriman, A.D., "A Dictionary of Metallurgy", MacDonald & Evans, Ltd, London, page 138, 1958
GW	AM	Hawley, Gessner G., The Condensed Chemical Dictionary (8 <sup>th</sup> ed.), New York, Van Nostrand Reinhold Company 1971, pg. 827.
GW	AN	Abstracts of the Japan Institute of Metals, "Formation Mechanism of Nano-crystal and Tabular Aligned Precipitate in Ti-Ni Sputtered Thin Film", No. 151, p. 165, September 28, 1996
GW	AO	KajiwarA et al., "Formation of nanocrystals with an identical orientation in sputter-deposited Ti-Ni thin films", Philosophical Magazine Letters, Vol. 74, No. 6, 395-404, December 1996

EXAMINER /George Wyszomierski/

DATE CONSIDERED 09/01/2006

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of form with next communication to applicant.